Thin-Film Design Refinement Via Efficient Parallel Combinatorial Search

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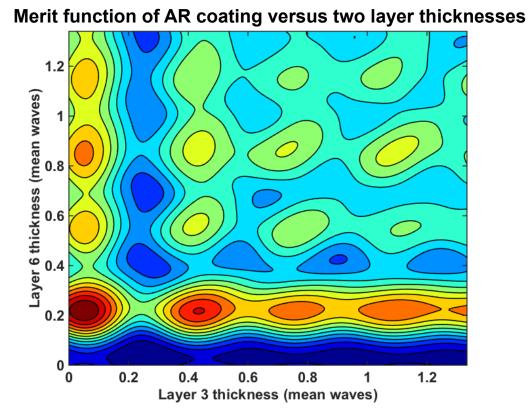
OIC 2016





Thin Film Merit Function Structure

• 14 layer AR coating on 1.52 substrate • Uniform thin layer initial conditions • low index: 1.35, high index: 2.35

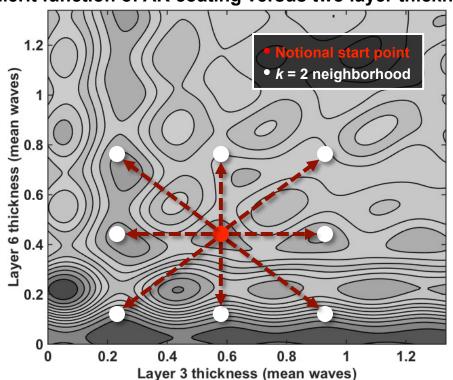


• Local minima tend to be spaced quasi-uniformly by 1/4- to 1/2-wave of mean optical thickness



Combinatorial Search Concept

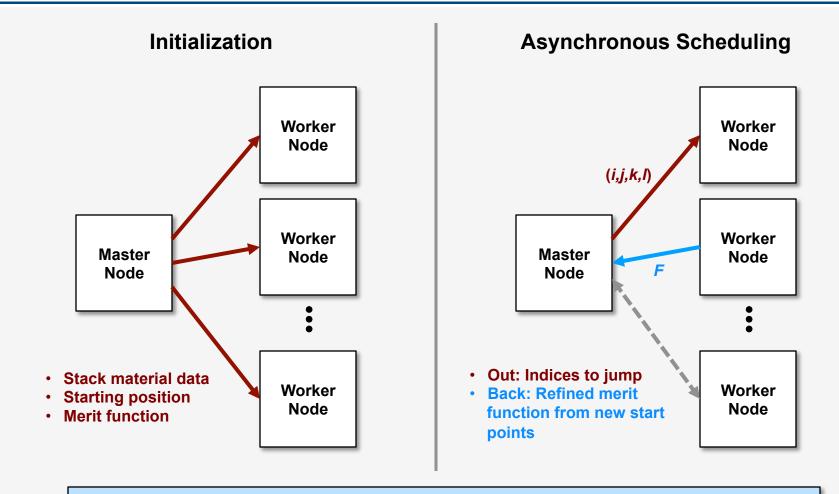
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Merit function of AR coating versus two layer thicknesses

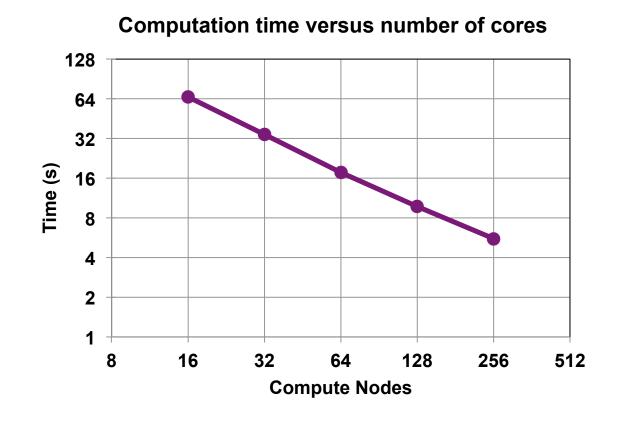
• Searching for better local minima can be done by simultaneously perturbing groups of *k* layers by enough to escape local minima and reoptimizing





Dynamic computation assignment prioritizes uniform node utilization over communication efficiency in the face of unpredictable computation times

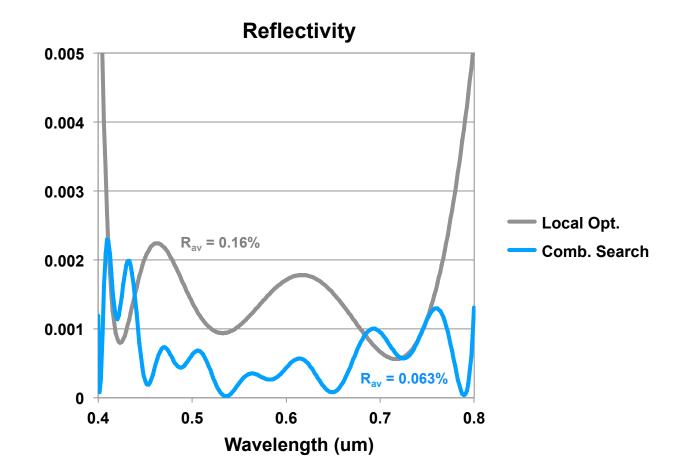




- Computation time scales linearly with processor count
- Parallel algorithm is not communication-limited



• 18 layer AR coating on 1.52 substrate • Low index: 1.38, high index: 2.35 • Trivial start point: uniform 1/20th mean wave layers • *k* = 2



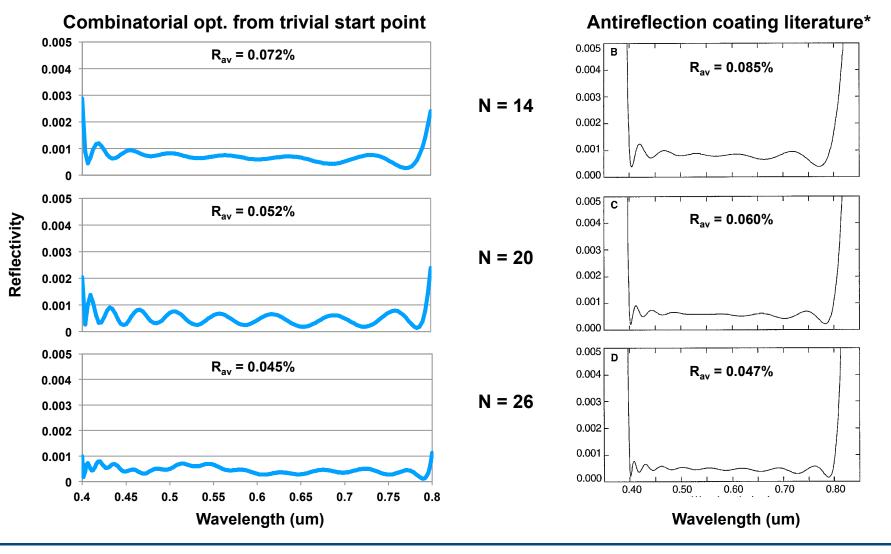
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AR Coating Design Results

• 14 layer AR coating on 1.52 substrate • Low index: 1.38, high index: 2.35 • k = 4 search space



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*J. A. Dobrowolski et al, "Optimal single-band normal-incidence antireflection coatings", Optics Letters 35 (1996)



- Test on other design genres
 - Initial work on stop/pass-band shows promise, albeit not as dramatic as AR coating
- Integrate into larger optimization schemes (e.g. gradual refinement, needle optimization, etc.)
- Adaptive jump size determination
- Implement on commodity cloud hardware (e.g. Amazon EC2)
- Integrate with manufacturing tolerance merit functions